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(71) Applicant *(for all designated States except US)*: **MICELL TECHNOLOGIES, INC.** [US/US]; 7516 Precision Drive, Raleigh, NC 27613 (US).

(72) Inventor; and

(75) Inventor/Applicant *(for US only)*: **WORM, Steve, L.** [US/US]; 4706 St. Thomas Place, Raleigh, NC 27612 (US).

(74) Agent: **BEATTY, David, D.**; Myers Bigel Sibley & Sajovec, P.O. Box 37428, Raleigh, NC 27627 (US).

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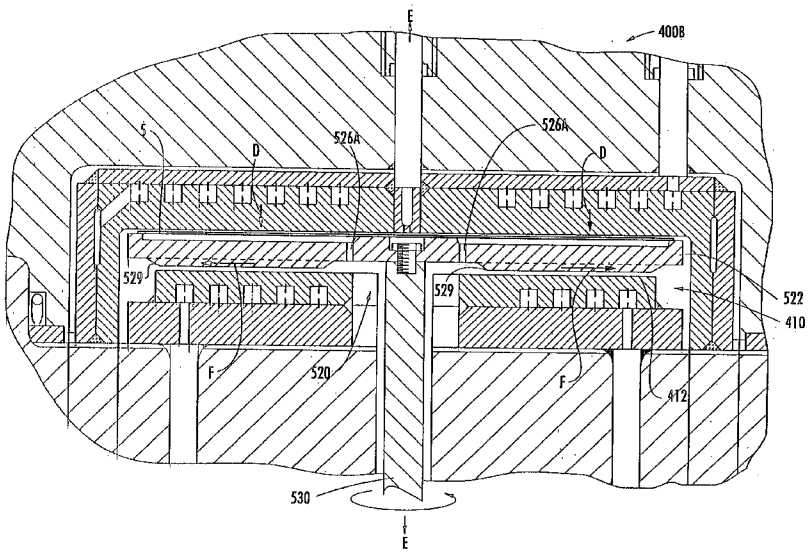
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(54) Title: METHODS AND APPARATUS FOR HOLDING A SUBSTRATE IN A PRESSURE CHAMBER



(57) Abstract: A process chamber assembly for use with a substrate includes a vessel and a substrate holder. The vessel defines a chamber. The substrate holder has a rotational axis and includes front and rear opposed surfaces. The front surface is adapted to support the substrate. At least one impeller vane extends rearwardly from the rear surface and radially with respect to the rotational axis. The impeller vane is operative to generate a pressure differential tending to hold the substrate to the substrate holder when the substrate holder is rotated about the rotational axis. Preferably, the process chamber assembly includes a plurality of the impeller vanes extending rearwardly from the rear surface and radially with respect to the rotational axis.

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